Challenges in Metrology & Analysis for next-generation semiconductor nodes

Advanced Metrology for Particle Sizing and Identification in Ultrapure Liquids

Gary Van Schooneveld, CT Associates October 18, 2021

CONNECT - COLLABORATE - INNOVATE - GROW - PROSPER



CTAssociates, Inc.



- Emerging Technologies
 - Liquid to Aerosol Conversion
 - Aerosol Particle Sizing and Counting
 - Focused Aerosol Deposition and Analysis
- Related SEMI Specifications

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Outline

Optical/Liquid Particle Counting (OPC/LPC)

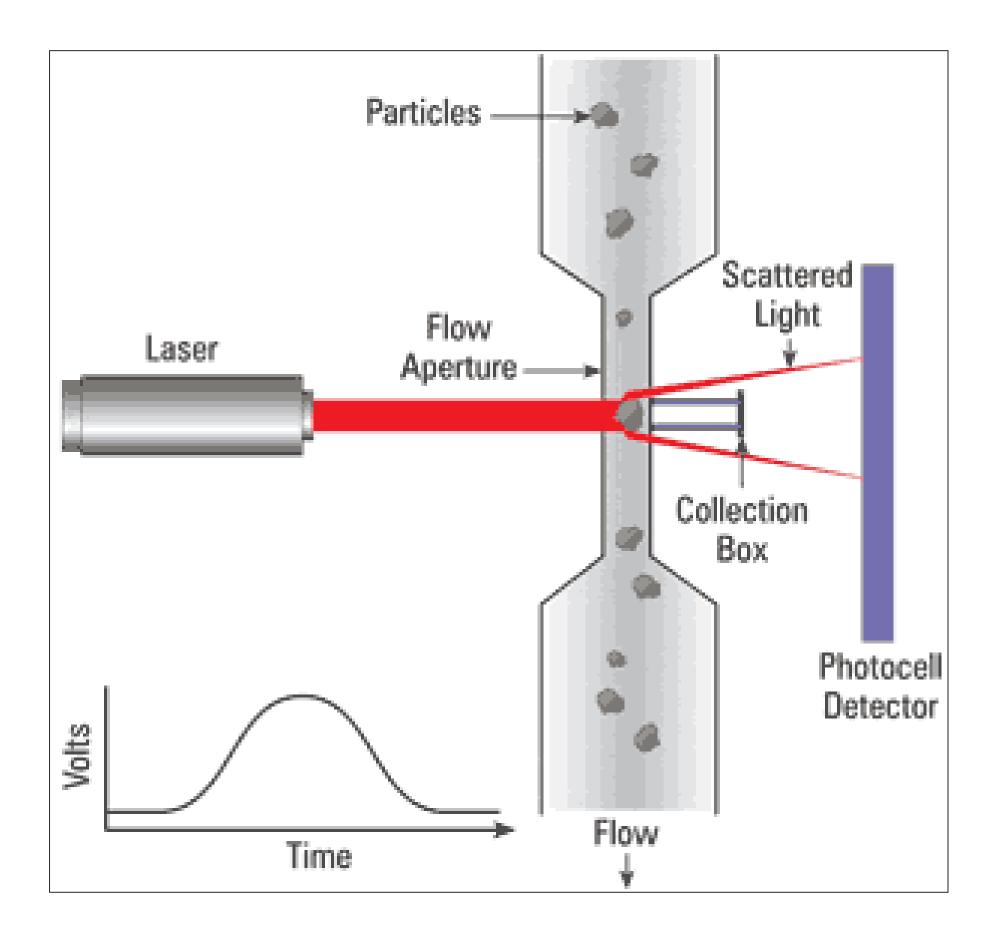




The OPC has been the semiconductor industry's particle workhorse for over 40 years.

How does an optical particle counter work?





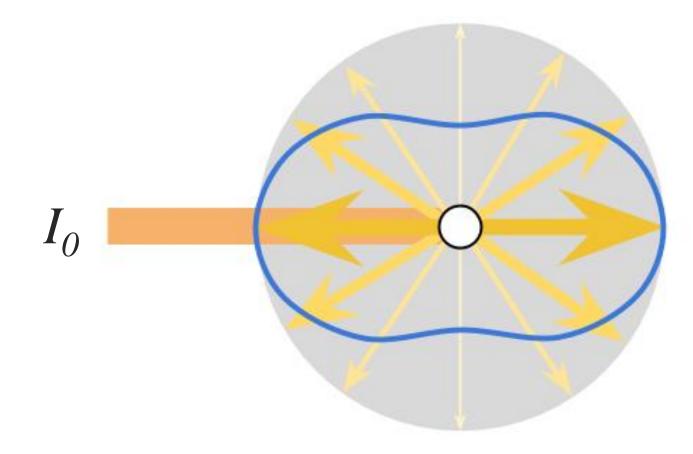
Courtesy of Noria Communications

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1. An optical counter is a scattered light event and intensity detector.





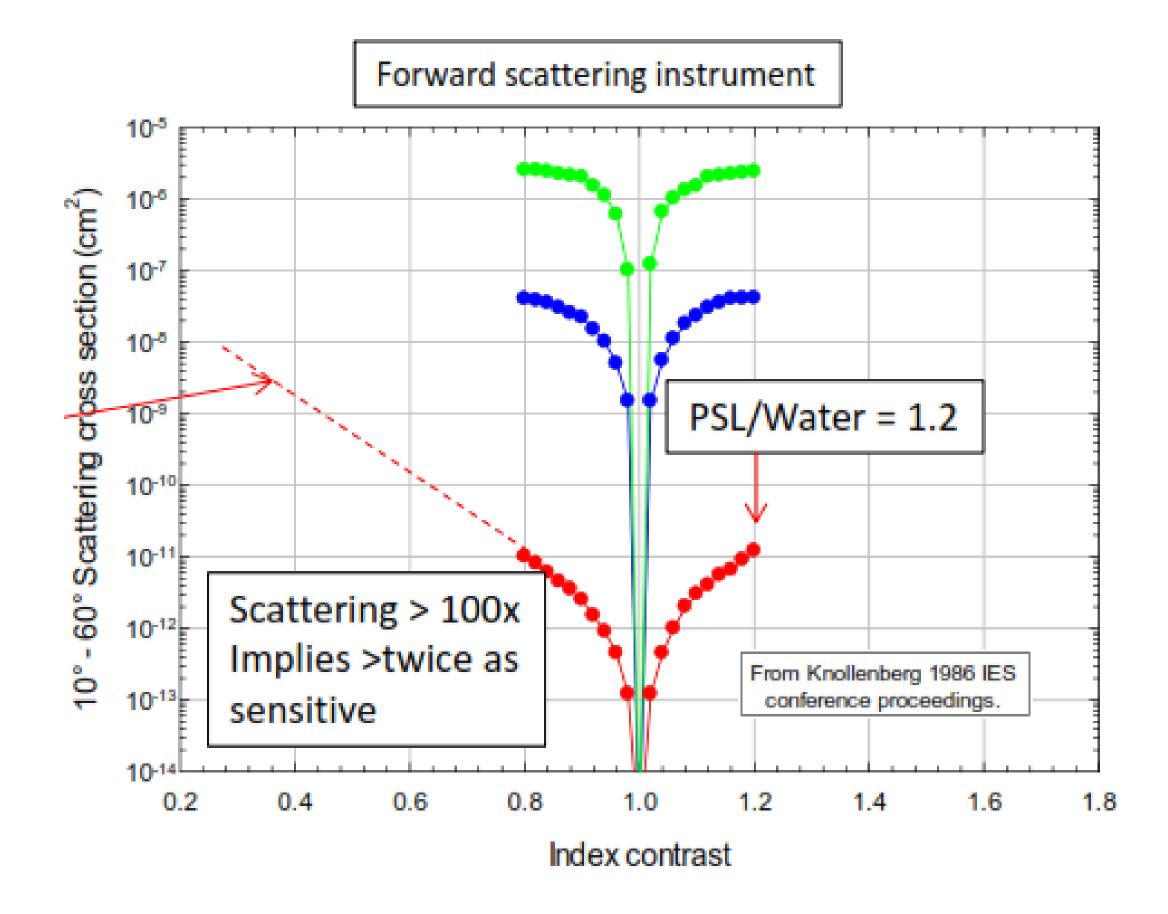


Rayleigh Scattering - Intensity of Light $\left(\frac{2\cdot\pi}{\lambda}\right)^4 \cdot \left(\frac{n^2-1}{n^2+2}\right)^2 \cdot \left(\frac{d}{2}\right)^6$

$$I = I_o \cdot \frac{1 + \cos(\theta)^2}{2 \cdot R^2} \cdot \left(\frac{2}{2}\right)$$

- 1. An optical counter is a scattered light event and intensity detector.
- 2. The intensity of the scattered light is proportional to "size" to 6th power (I $\propto D_{\rm p}^{6}$).





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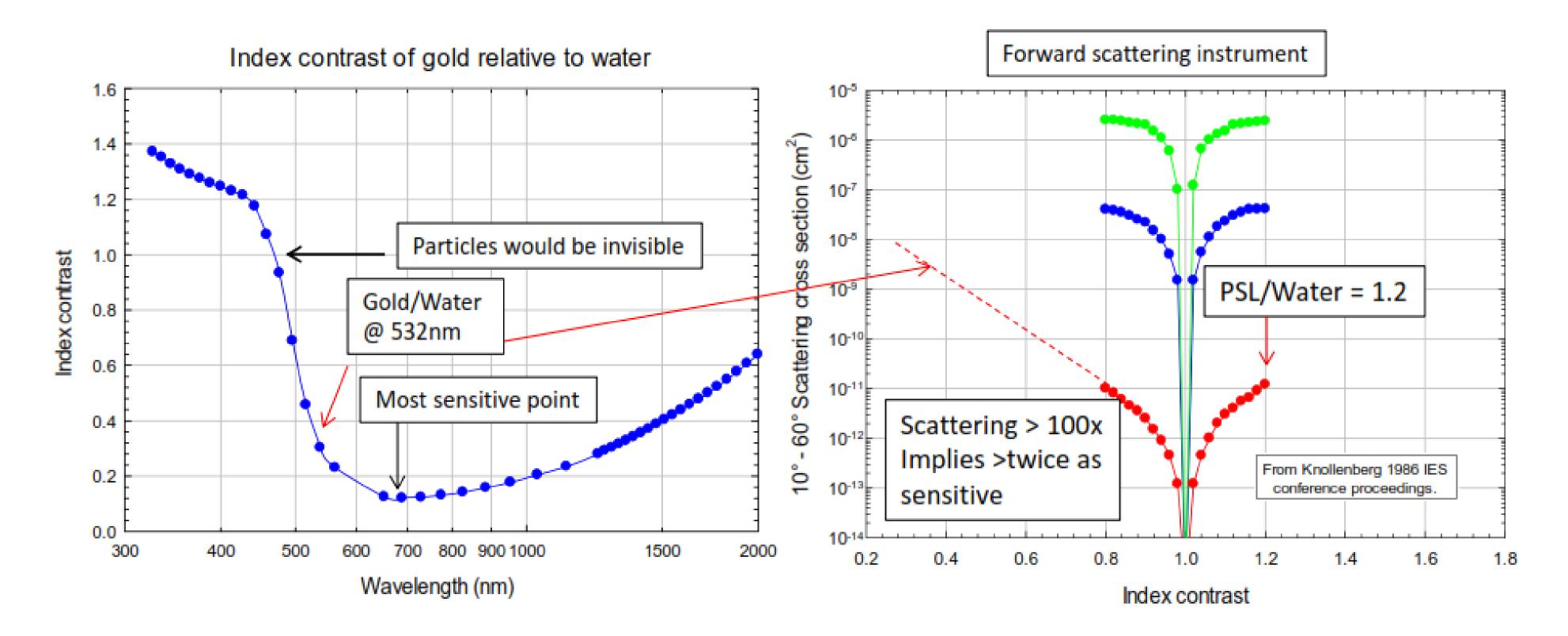
- 1. An optical counter is a scattered light event and intensity detector.
- 2. The intensity of the scattered light is proportional to "size" to 6th power (I $\propto D_p^{-6}$).
- 3. The actual size of the particle may be different that the reported size due to material composition and liquid.

 $Index \ contrast = \frac{Particle \ refractive \ index}{Medium \ refractive \ index}$









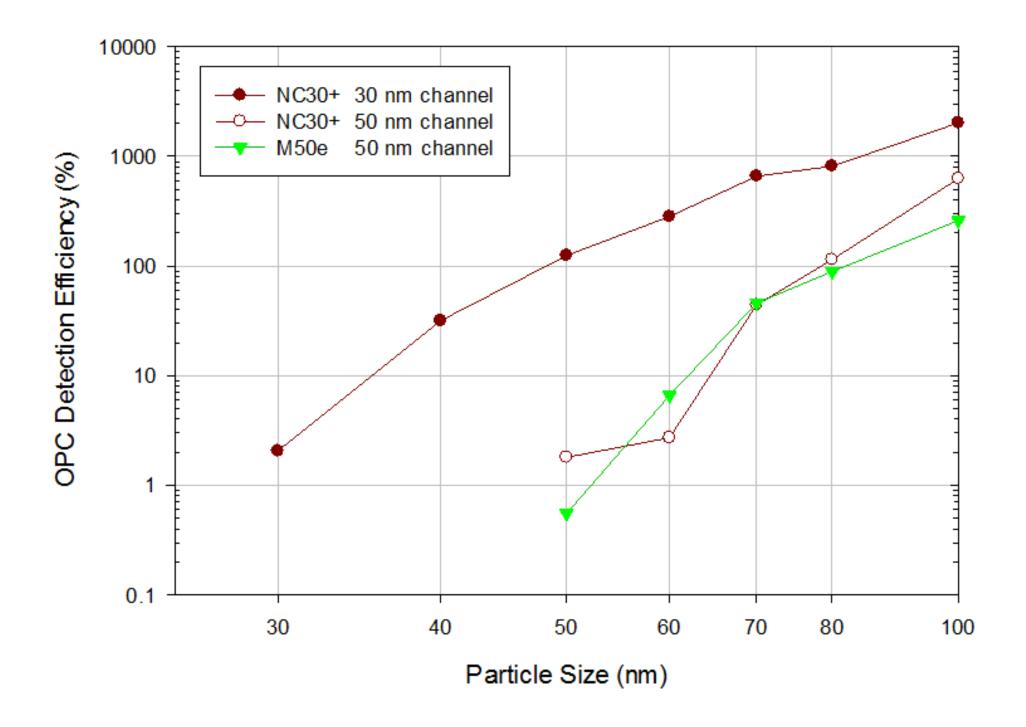
A 20 nm gold particle in water has roughly the same light-scattering cross-section of a 45 nm PSL particle. However, a 20 nm PTFE particle in water would size closer to 10 nm

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Optical Particle Counting



OPC response to mono-dispersed PSL



Source: Van Schooneveld, et al., UPW Micro 2013

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- 2. The intensity of the scattered light is proportional to "size" to 6th power (I \propto D_{p}^{6}).
- 3. The actual size of the particle may be different that the reported size due to material composition and liquid.
- 4. Detection efficiency varies significantly as a function of size.

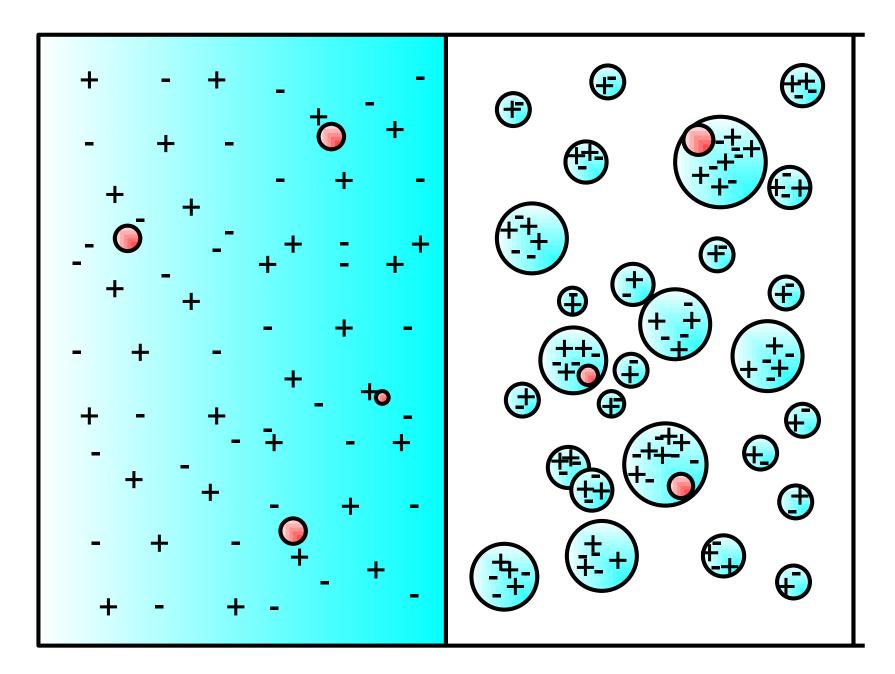


Liquid to Aerosol Conversion

Liquid to aerosol conversion was first introduced to the semiconductor industry in 2008 for CMP slurry PSD and UPW particle measurement.

How does liquid to aerosol conversion work?





Liquid Sample With NVR

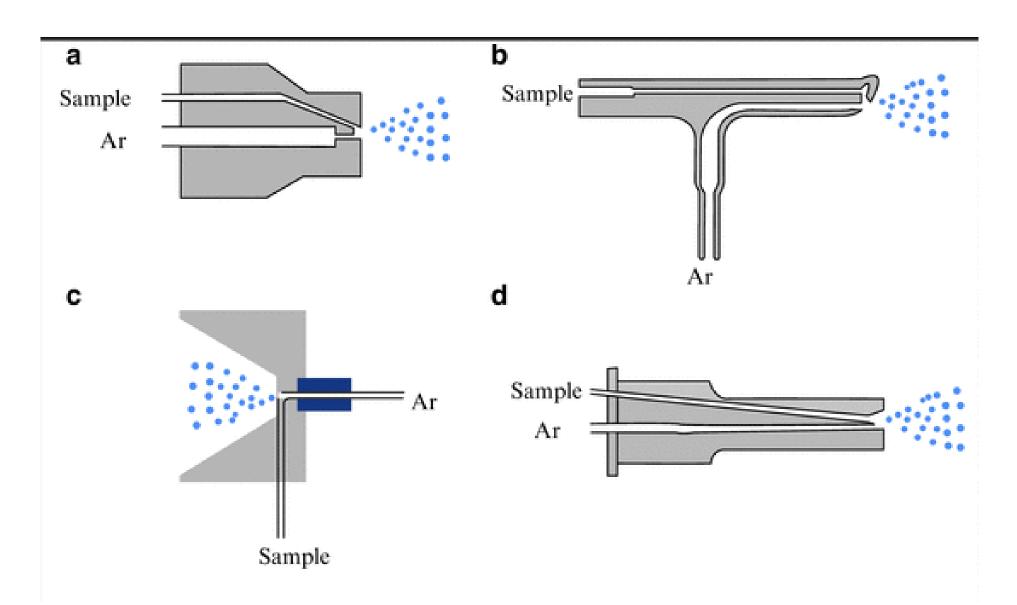
Nebulized Sample

Courtesy of Kanomax FMT

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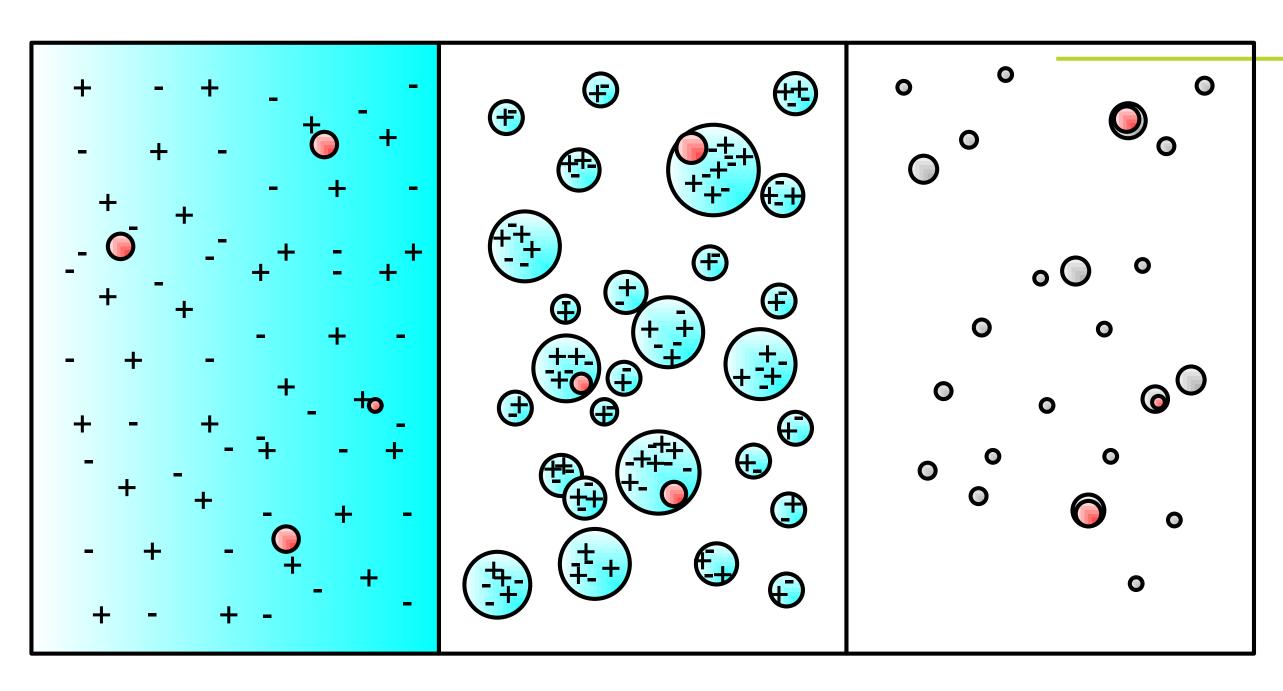
1. Objective is to convert liquid into small, uniform droplets.







Liquid to Aerosol Conversion



Liquid Sample With NVR

Nebulized Sample

Aerosolized Sample

Courtesy of Kanomax FMT

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- 1. Objective is to convert liquid into small, uniform droplets.
- 2. Remove liquid from the droplets leaving "native" and "formed" particles from particle precursors*.

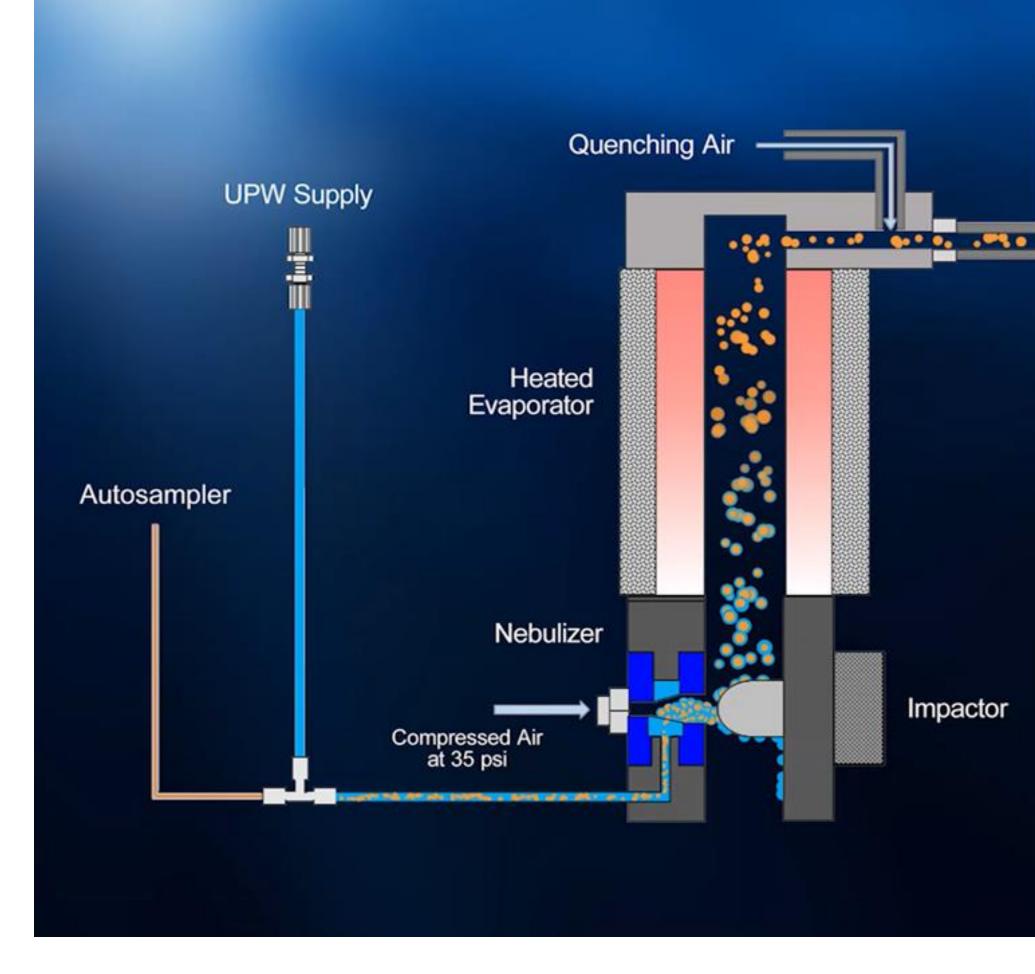
* The risk of particle precursors forming particles of critical dimension during manufacturing is currently being study in the IRDS UPW and Critical Components Task Forces.





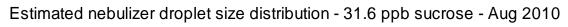
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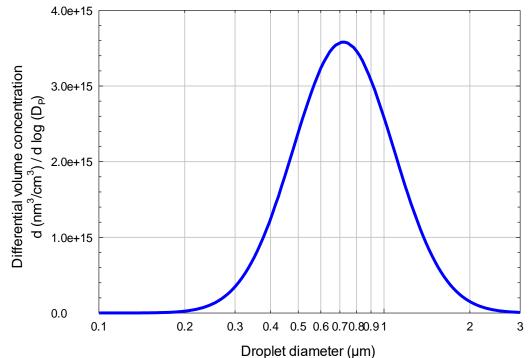
Liquid to Aerosol Conversion

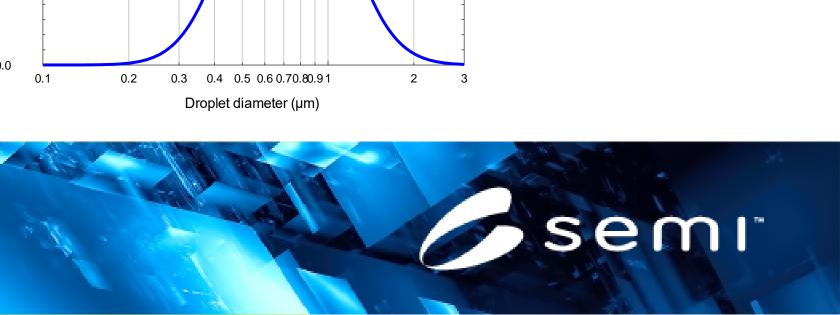


Courtesy of Kanomax FMT

- 1. Objective is to convert liquid into small, uniform droplets.
- 2. Remove liquid from the droplets leaving "native" and "formed" particle (particle precursors).
- 3. Achieving small (<1 μ m), uniform (geo SD < 1.2) droplet distribution is key to the success of this technique.



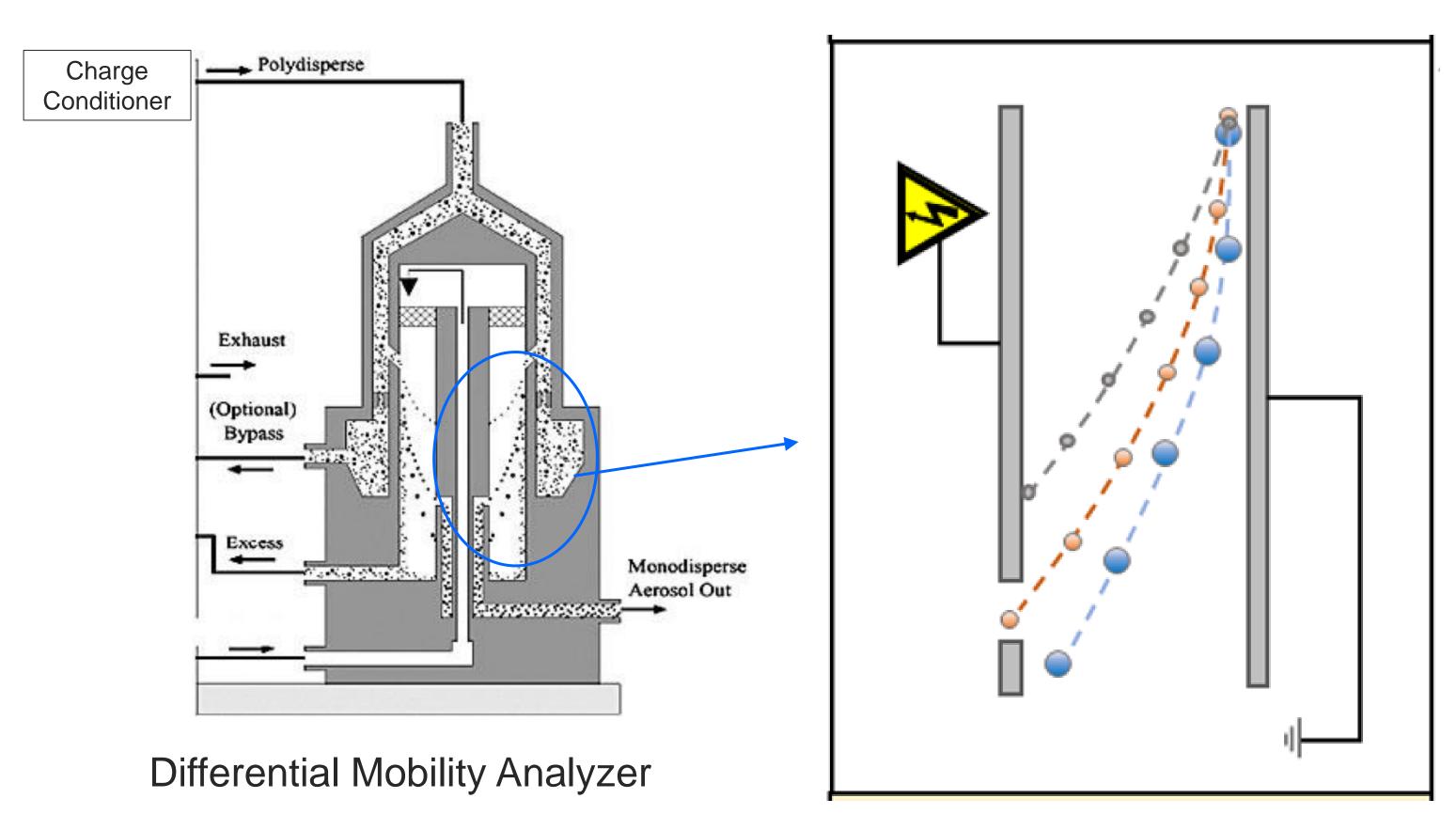




Aerosol classification (sizing) and counting as small as 10 nm was demonstrated in the mid-1970's and commercialize in the early 1980's.

How does aerosol particle sizing and counting work?





Electrical mobility $\propto D_p$

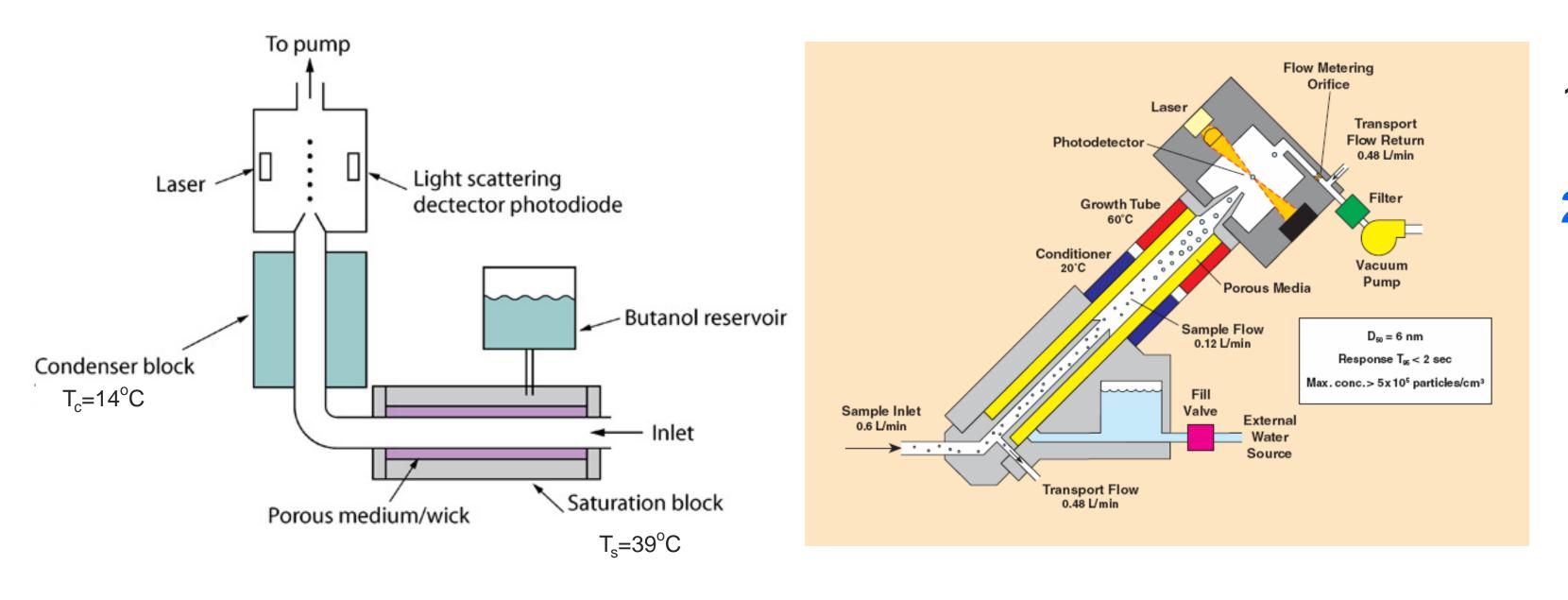
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1. Electrical mobility classification - sizing

Sizing technique used in Liquid Nanoparticle Sizing (LNS)



Detection to < 2 nm available



Butanol Based CPC

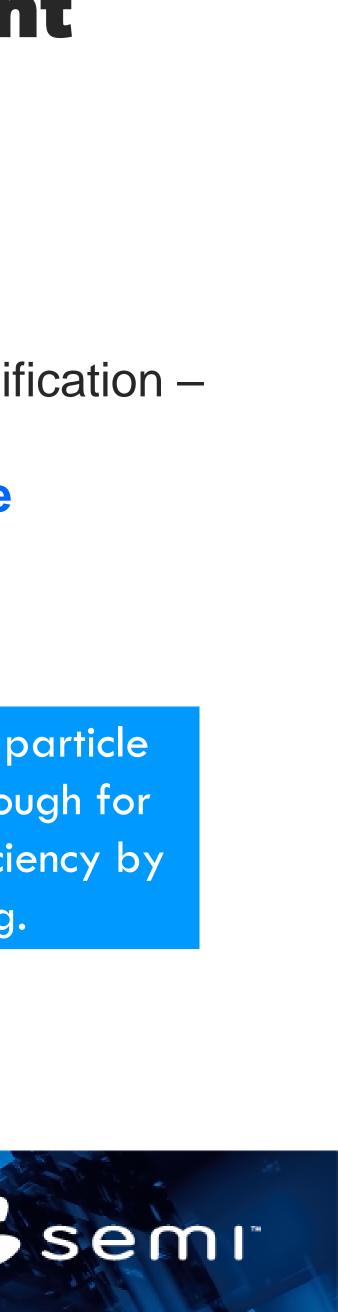
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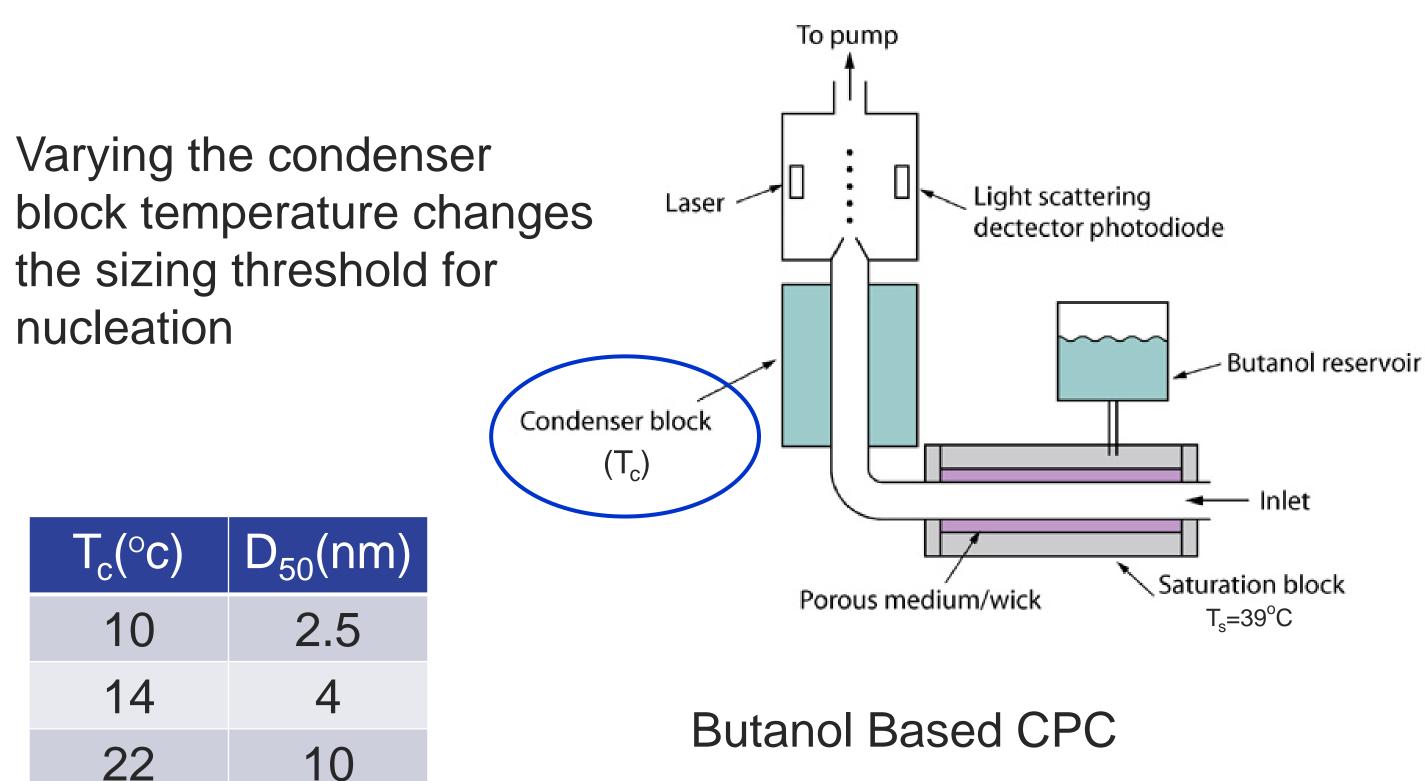
Water Based CPC

- Electrical mobility classification 1. sizing
- **Condensation particle** 2. counting (CPC)

Liquid condenses on particle and grows large enough for 100% detection efficiency by light scattering.







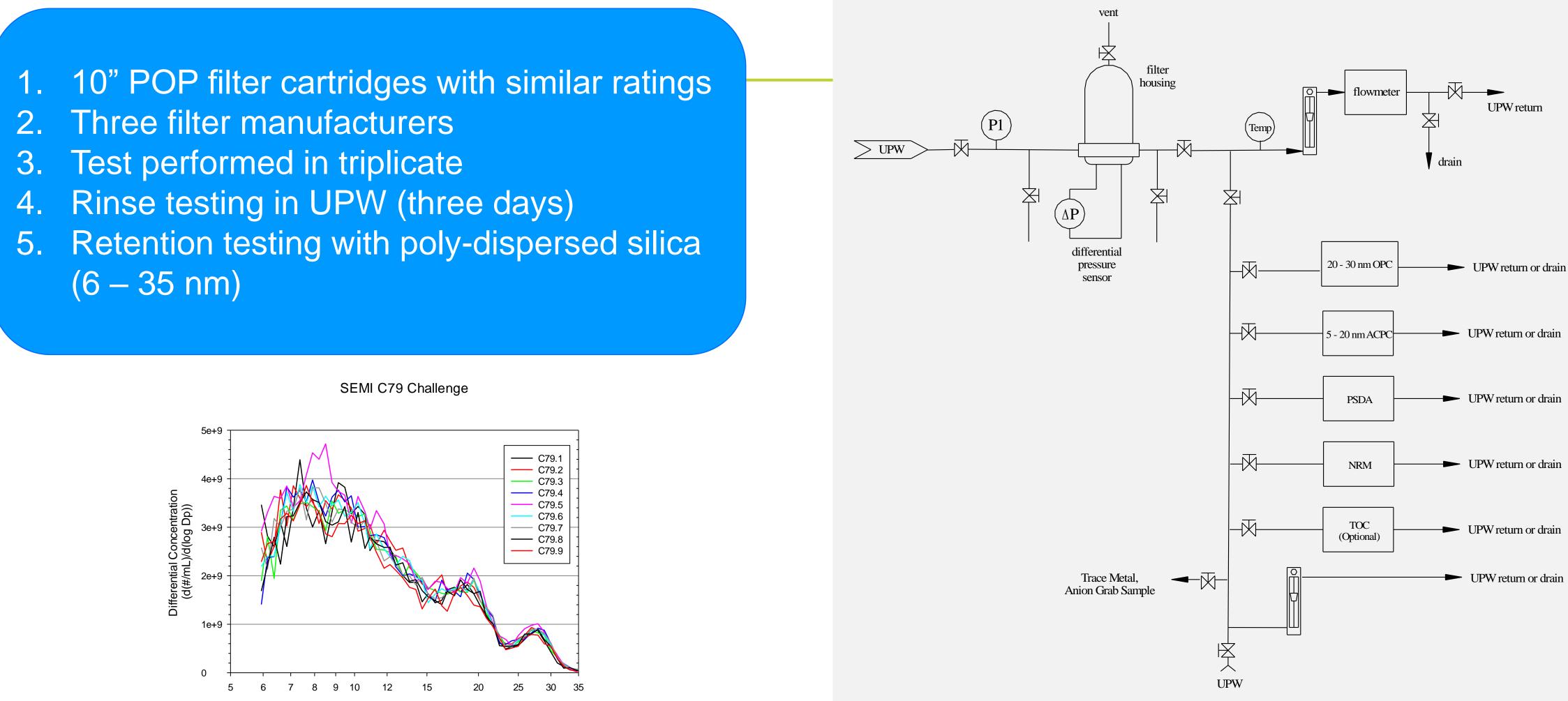
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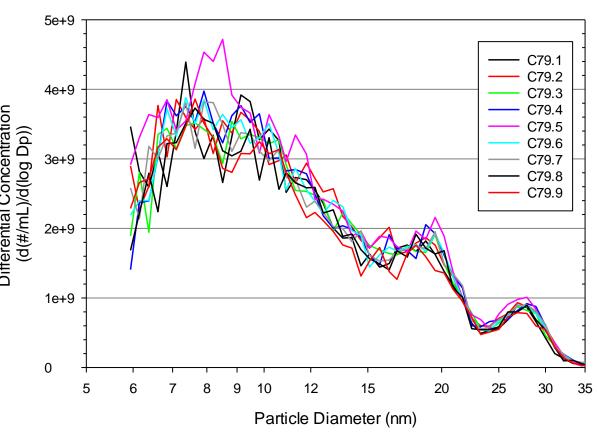
- Electrical mobility classification sizing
- 2. Condensation particle counting (CPC)
- 3. Variable D₅₀ cutoff CPC's -Sizing

Sizing technique used in the Scanning Threshold Particle Counter (STPC)

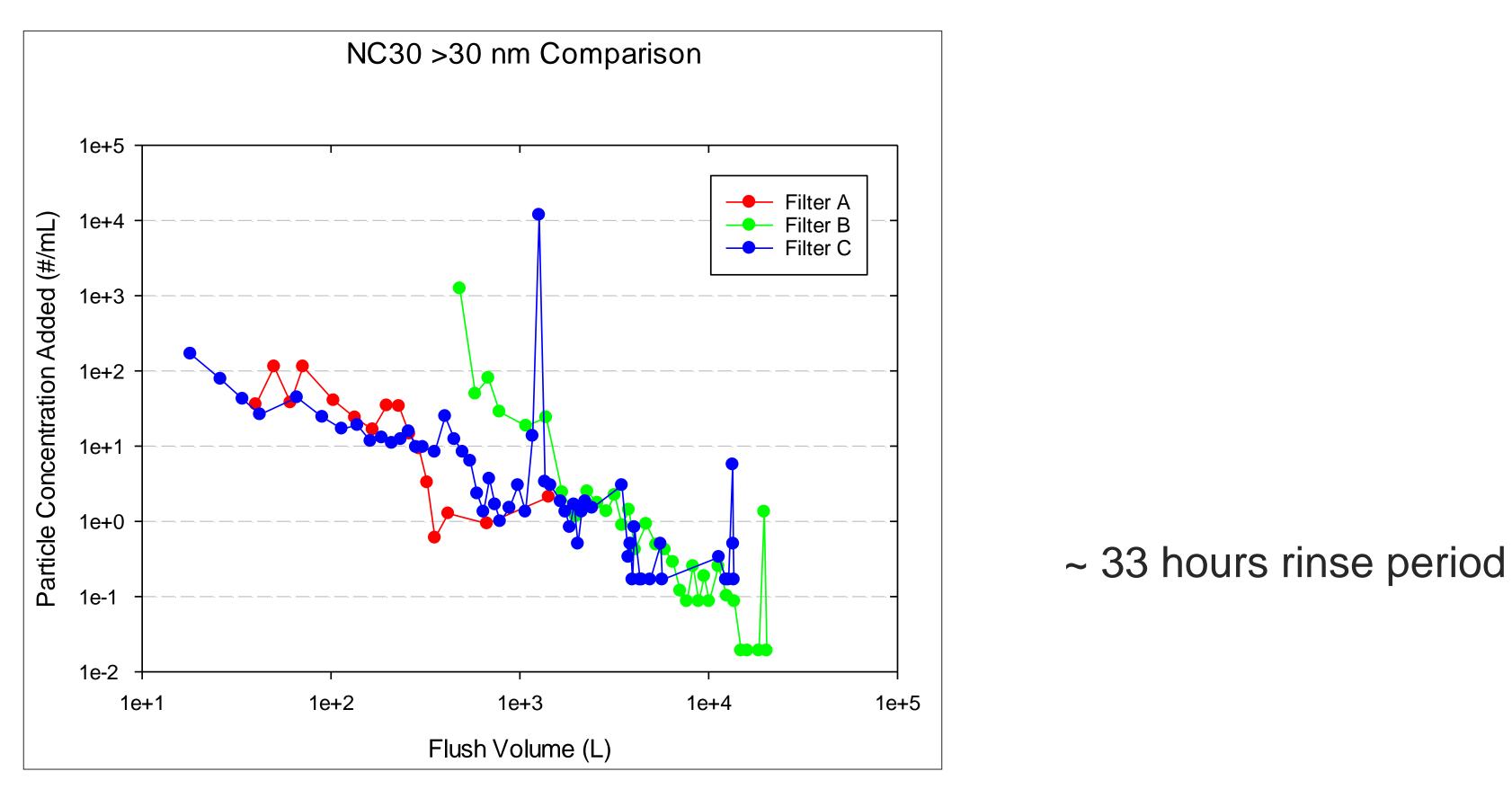












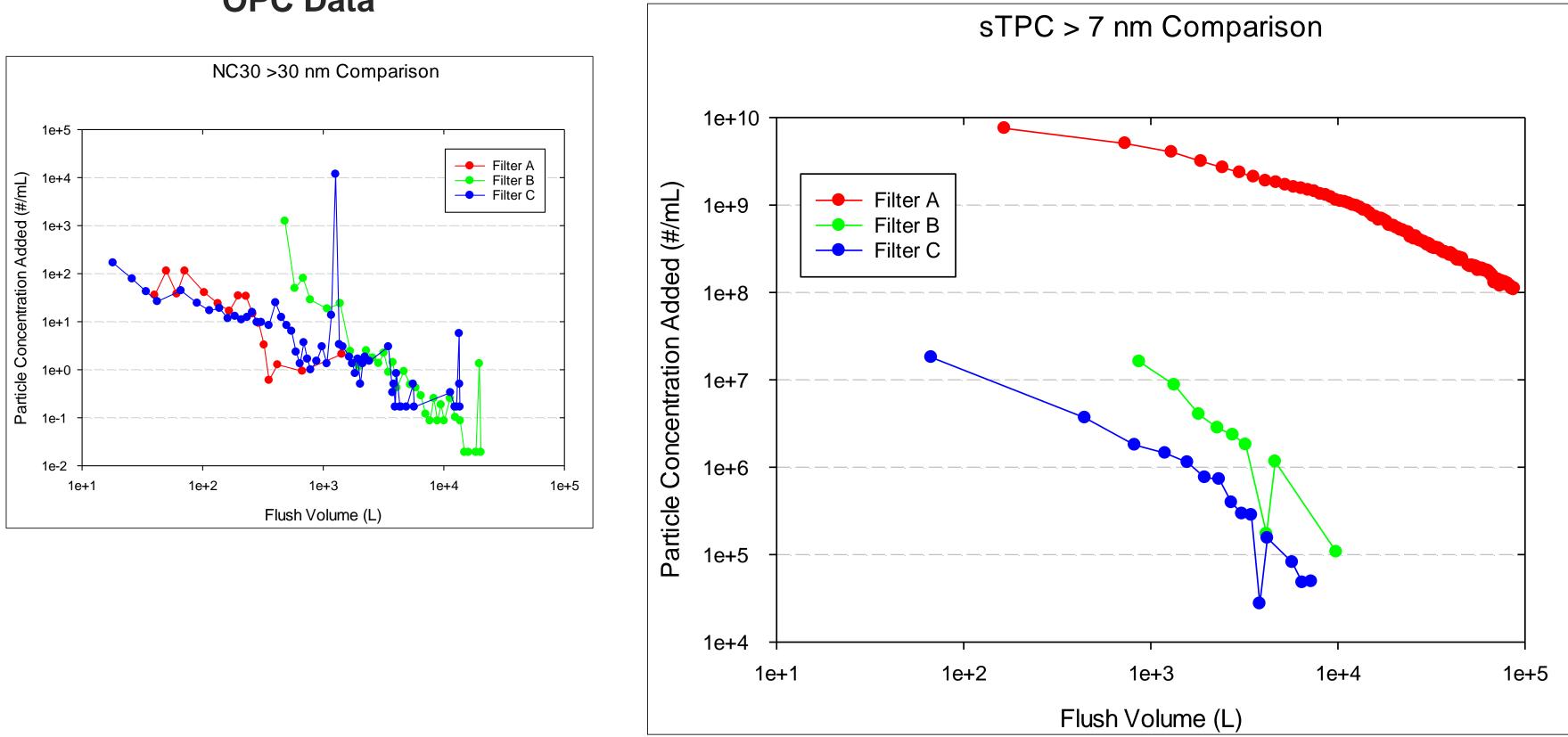
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OPC Data





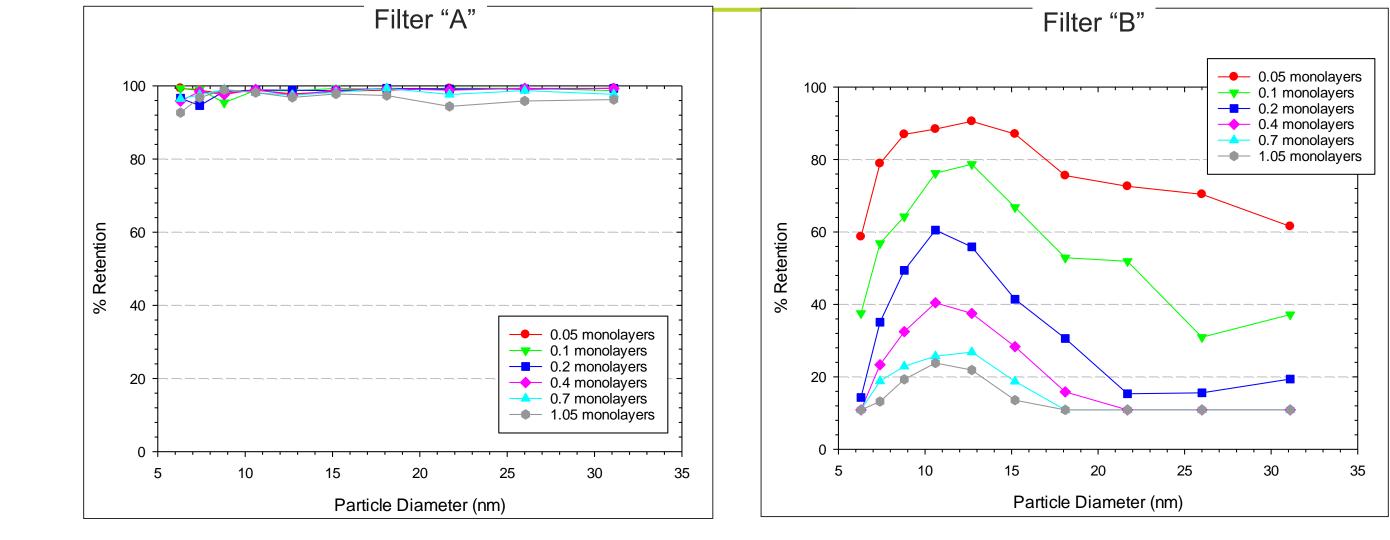
Liquid to Aerosol - CPC

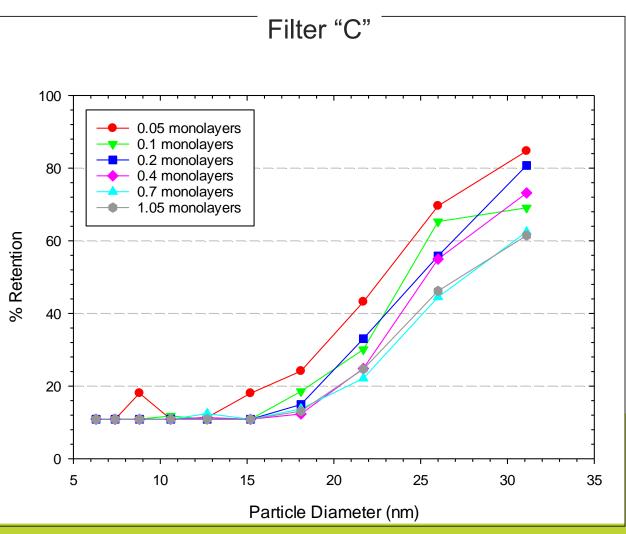


OPC Data



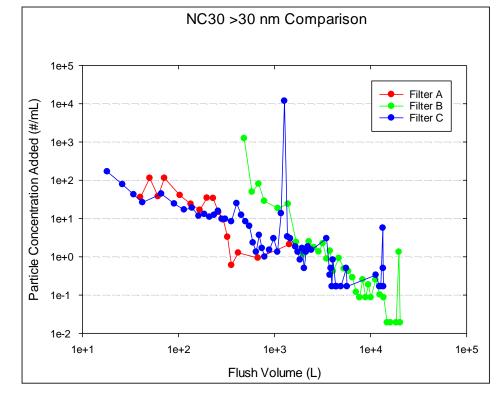
Liquid to Aerosol – EM Classification



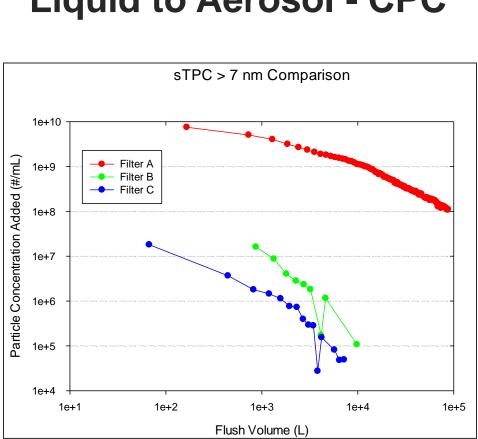


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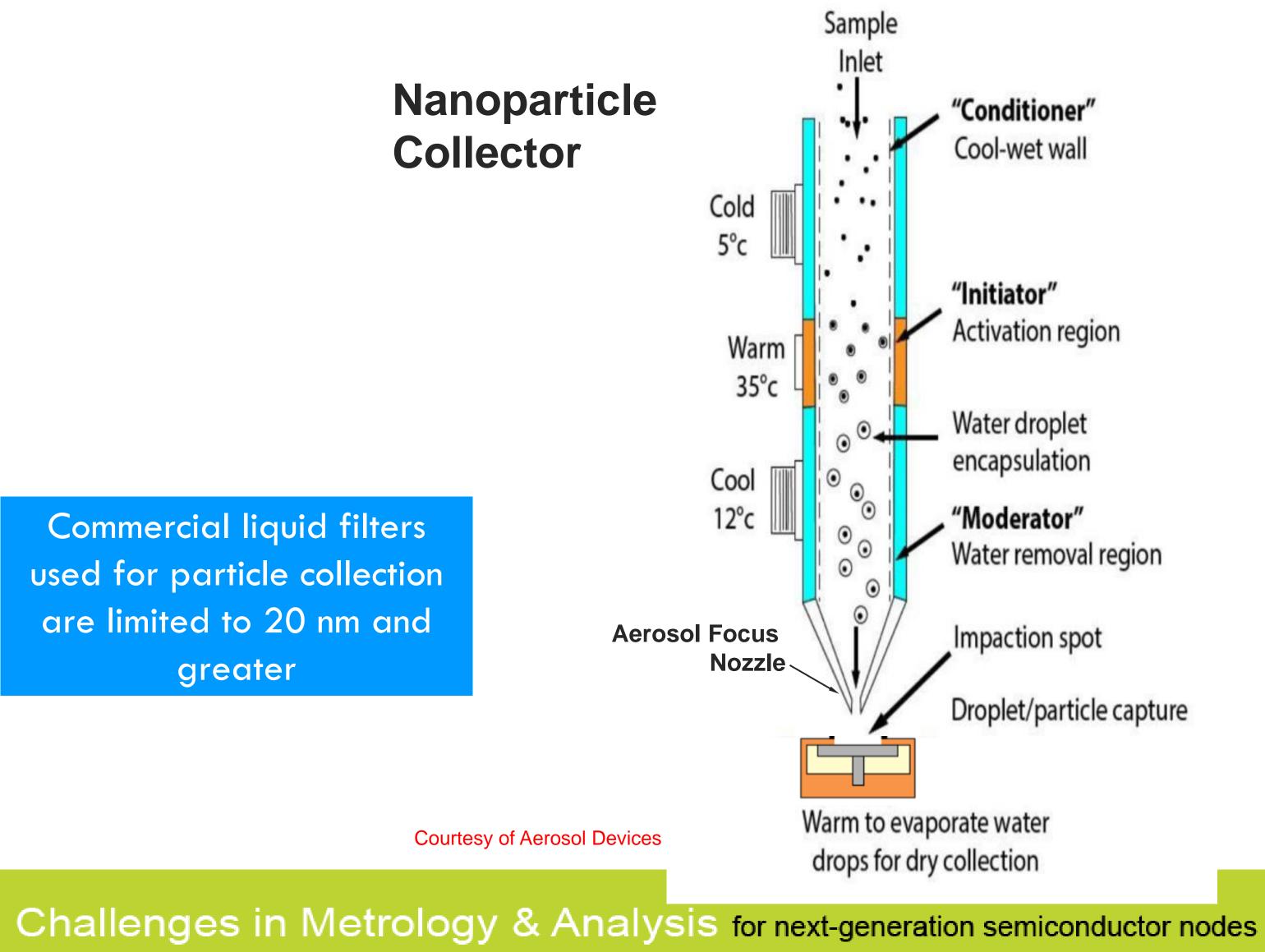
Focused Aerosol Deposition (FAD) and Analysis

Ability to collect, concentrate and deposit extracted nanoparticles as small as 5 nanometers was first demonstrated in 2017.

How does FAD work?



Focused Aerosol Deposition (FAD) and Analysis



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"Conditioner" Cool-wet wall

"Initiator" Activation region

Water droplet encapsulation

"Moderator" Water removal region

Impaction spot

Droplet/particle capture

Supersaturation levels of 120-140% activate condensation growth on particles as small as 3 nm.

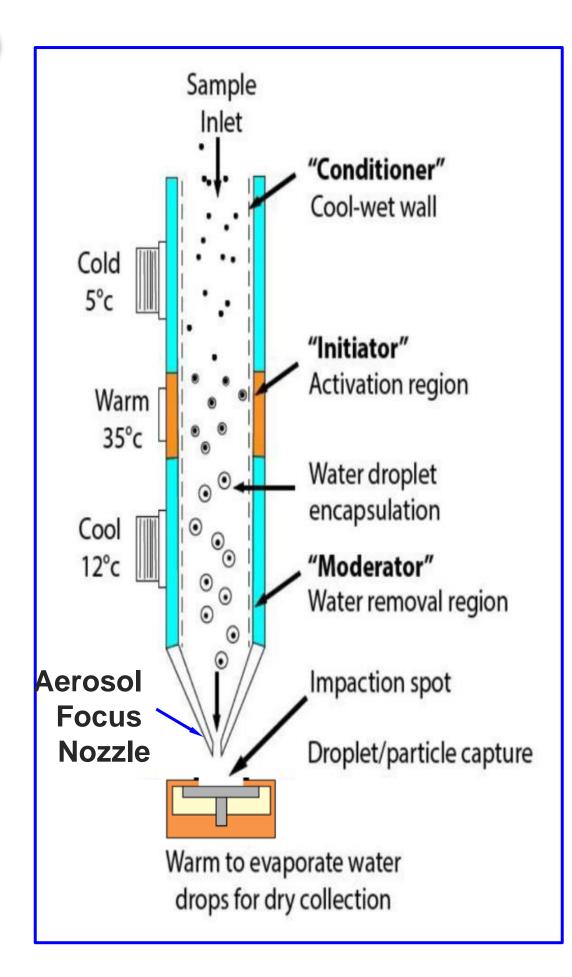
Droplets grown to nominal 3µm diameter are easily captured by bounce-free, soft inertial impaction.



Focused Aerosol Deposition (FAD) and Analysis

Nanoparticle Collector

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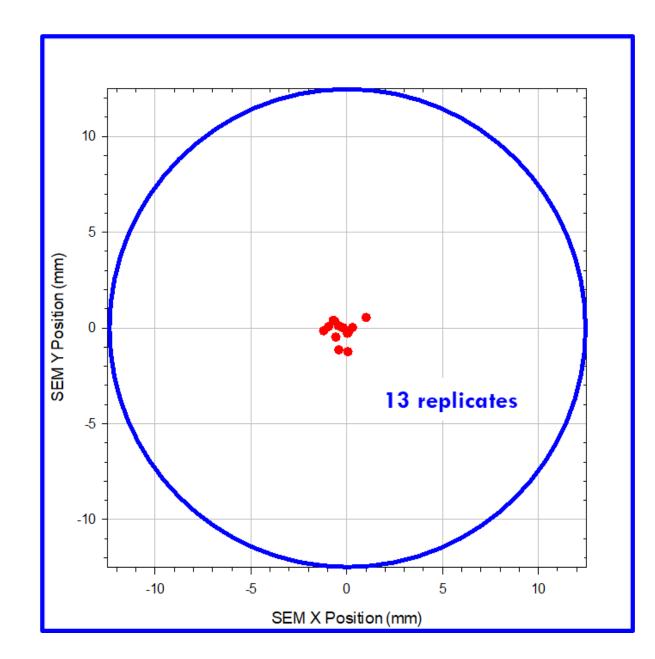




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Collection Media: **EPI Silica Wafer EPI** Germanium Wafer SERS Ready Wafer TOF-SIMS Ready Wafer

Collection Focus Repeatability

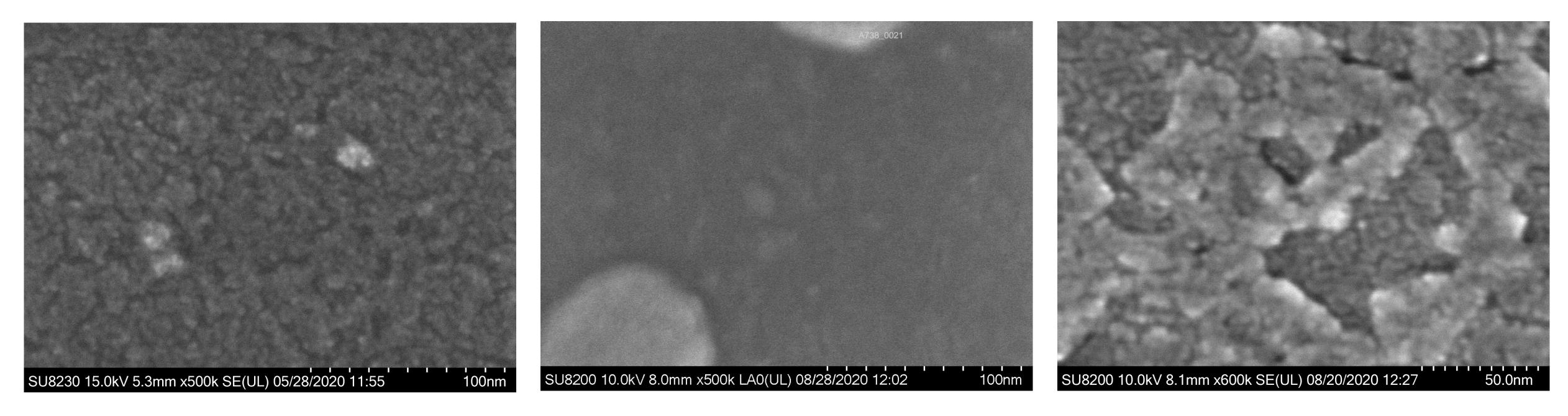






FAD Collections Examples – SEM Analysis

Ion Exchange Resin Effluent



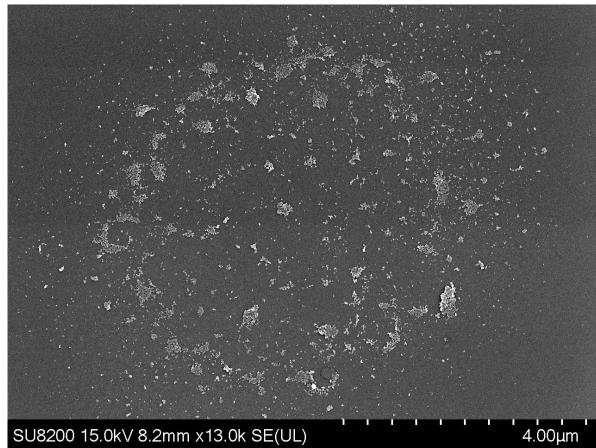
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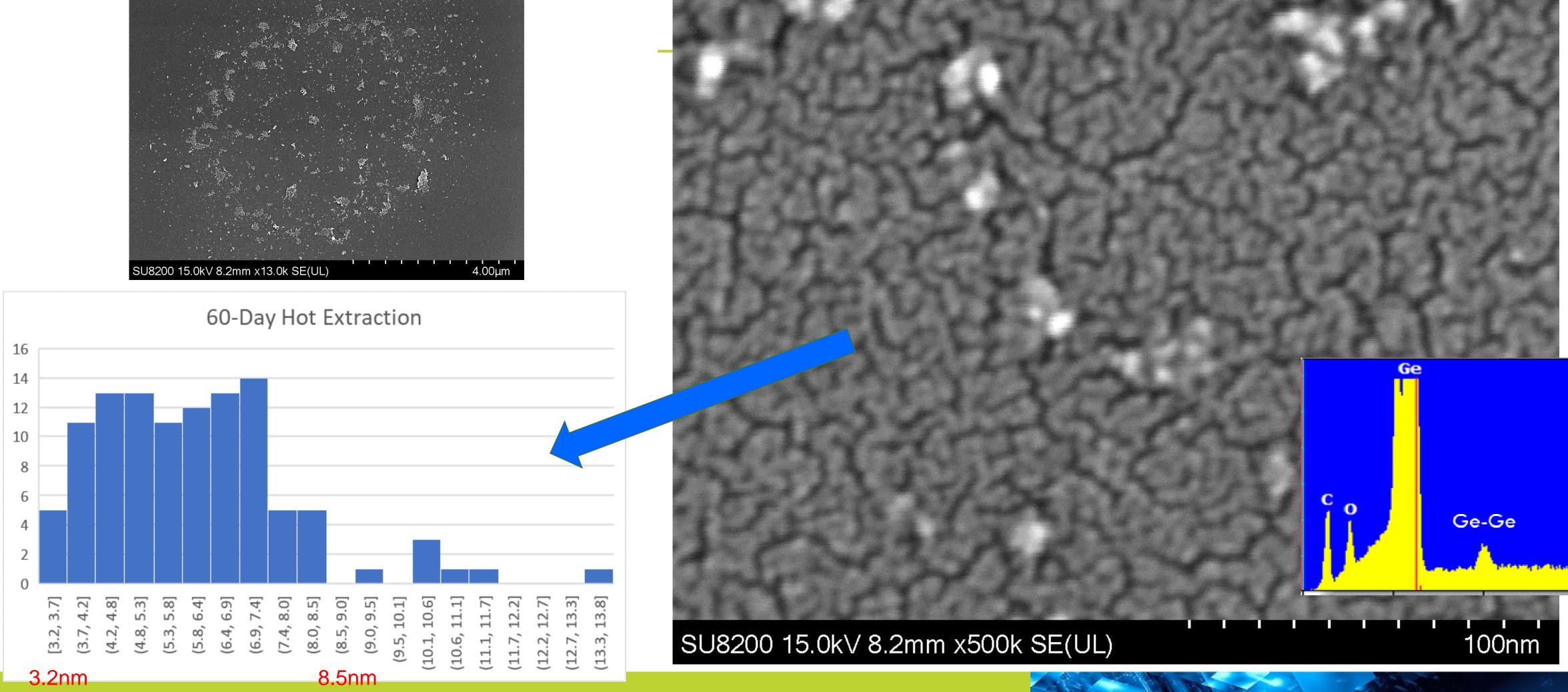
Hot UPW Fluoropolymer Piping Extract





FAD Collection Example – SEM/EDX/PSD Analysis







Key Takeaways

- economic limit (15 to 20 nm).
- efficiency.
- Focused aerosol deposition in conjunction with surface analysis of nano-contamination at sizes previously not possible.

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Liquid optical particle counting appears to be reaching its practical and

 Liquid to aerosol conversion and sizing techniques have demonstrated capabilities to measure particles as small as 2 nm with high detection

techniques provides a tool for determining the composition and source









semi;

Related Subject Matter- SEMI Specifications

- SEMI C77 Test Method for Determining the Counting Efficiency of Liquid-Borne Particle Counters for Which the Minimum Detectable Particle Size is Between 30 nm and 100 nm
- SEMI C79 Guide to Evaluate the Efficacy of Sub-15 nm Filters Used in Ultrapure Water (UPW) Distribution Systems
- SEMI C82 Test Method for Particle Removal Performance of Liquid Filter Rated 20 to 50 nm With Liquid-Borne Particle Counter
- SEMI C93 Guide for Determining the Quality of Ion Exchange Resin Used in Polish Applications of Ultrapure Water System SEMI C98 - Guide for Chemical Mechanical Planarization (CMP) Particle Size Distribution (PSD) Measurement and Reporting
- Used in Semiconductor Manufacturing
- SEMI F75 Guide for Quality Monitoring of Ultrapure Water Used in Semiconductor Manufacturing
- SEMI F104 Test Method for Evaluation of Particle Contribution of Components Used in Ultrapure Water and Liquid Chemical **Distribution Systems**
- SEMI F110 Test Method for Mono-Dispersed Polystyrene Latex (PSL) Challenge of Liquid Filters

